Amendment dated: February 29, 2008 Reply to OA of: November 29, 2007

This listing of claims will replace all prior versions and listings of claims in the application.

Listing of Claims:

1(original). A vertical sublimation apparatus, comprising:

a sublimation channel body;

a material rack for storing materials that will be evaporated;

a heating evaporation device surrounding an evaporation pipe to control heating temperatures according to different materials for evaporating said materials;

a condensation device surrounding the upper part of said sublimation channel body for controlling condensation temperatures required by different evaporated materials:

an incubating device for maintaining the temperatures of both the vapor channel and end products; and

a product scratching device.

2(currently amended). The vertical sublimation apparatus as claimed in claim 1, wherein the structure of said material rack comprises a plurality of rails and fixed rings, and said rails being are fixed by two fixed rings and being located in said evaporation pipe for storing materials ready to be evaporated.

3(currently amended). The vertical sublimation apparatus as claimed in claim 1, wherein said incubating device comprises a vapor channel incubating device and a product incubating device, and said vapor channel incubating device <u>surrounds</u> surrounding an outlet port of said vapor channel to maintain the temperature of the sublimated vapor and <u>transports</u> transporting said sublimated vapor continuously into said sublimation channel body.

Amendment dated: February 29, 2008

Reply to OA of: November 29, 2007

4(original). The vertical sublimation apparatus as claimed in claim 3, wherein said

product incubating device surrounds the lower part of said sublimation channel body to

avoid accumulation of said sublimated vapor.

5(original). The vertical sublimation apparatus as claimed in claim 1, wherein said

product scratching device comprises a central axis for shifting up and down and/or

rotating said product scratching device, fixed rings, central support and sawtooth.

6(original). The vertical sublimation apparatus as claimed in claim 5, wherein said

sawtooth is located near said fixed rings beneath said central support for scratching off

condensed products from the wall of said sublimation channel body.

7(original). The vertical sublimation apparatus as claimed in claim 1, wherein said

lower part of said sublimation channel body is formed as a product storage tank for

collecting said condensed products falling therein after being scratched off by said

scratching device.

8(original). The vertical sublimation apparatus as claimed in claim 1, further

comprising heat shield devices made of quartz wool and located at two ends of said

sublimation channel body with one end of said evaporation pipe being further away from

said sublimation channel body for maintaining a certain temperature inside said

sublimation apparatus.

9(currently amended). The vertical sublimation apparatus as claimed in claim 1,

further comprising sealing caps located at each end of said channels having with heat

shield devices placed therein and locked by O-rings to prevent vacuum leakage.

10(withdrawn). A horizontal sublimation apparatus, comprising:

a sublimation channel body;

-4-

Amendment dated: February 29, 2008 Reply to OA of: November 29, 2007

a material carrier located inside said sublimation channel body for storing materials ready to be evaporated;

a heating evaporation device surrounding an evaporation pipe to control heating temperatures according to different materials for evaporating said materials;

an end pipe mounted respectively at two ends of said sublimation channel body with one said end pipe connecting to a vacuum air extracting system and the other said end pipe being sealed; and

a pipe-end sealing device for connecting two ends of said sublimation channel body to said two end pipes for achieving preferable sealing effect of said sublimation channel body.

11(withdrawn). The horizontal sublimation apparatus as claimed in claim 10, wherein material carrier can be in the shape of a boat, a tank, a circular plate or any other forms that can be used to store materials.

12(withdrawn). The horizontal sublimation apparatus as claimed in claim 10, wherein said pipe-end sealing device is a screw nut.

13(withdrawn-currently amended). A vapor collection device, comprising: a collecting bottle filled with wires for expanding the contacting surface between vapor and cold temperature surface;

an inlet pipe for connecting with said vacuum sublimation purification apparatus, such that so the uncondensed vapor can be guided into said collecting bottle; and an exhaust pipe for connecting with said vacuum extraction system.

14(withdrawn). The vapor collection device as claimed in claim 13, wherein said vapor collection device is disposed between said sublimation channel body and said vacuum system for condensing said uncondensed vapor via low temperature, thus preventing said vacuum pump from being contaminated.

Amendment dated: February 29, 2008 Reply to OA of: November 29, 2007

15(withdrawn-currently amended). A vacuum sublimation purification process applied to said vertical sublimation purification apparatus of claim 1,comprising the following steps:

placing materials on said material rack;

turning on said vacuum extraction device to vacuum;

turning on said heating evaporation device to achieve the required sublimation temperature of materials;

turning on all incubating devices to maintain the condensation temperature; scratching and collect collecting products at a regular time interval during the evaporation process; and

cooling down the temperature after evaporation is completed and take taking out products from said product storage tank.

16(withdrawn). The vacuum sublimation purification process as claimed in claim 15, wherein conditions of sublimation required for purifying Alq₃ are: evaporation temperature being 350~450°C, condensation temperature being 250~350°C, evaporation temperature being 50~100°C higher than condensation temperature, and system pressure being 1~1 10⁻⁶ mbar.

17(withdrawn). The vacuum sublimation purification process as claimed in claim 15, wherein conditions of sublimation for purifying NPB are: evaporation temperature being 250~350°C, condensation temperature being 150~250°C, evaporation temperature being 30~80°C higher than condensation temperature, and system pressure being 0.1~1 10⁻⁶ mbar.

18(withdrawn). The vacuum sublimation purification process as claimed in claim 15, wherein conditions of sublimation for purifying CuPc are: evaporation temperature being 500~650°C, condensation temperature being 400~500°C, evaporation

Amendment dated: February 29, 2008 Reply to OA of: November 29, 2007

temperature being 50~100°C higher than condensation temperature, and system pressure being 0.1~1 10⁻⁶ mbar.

19(withdrawn-currently amended). A vacuum sublimation purification process applied to said horizontal sublimation purification apparatus of claim 10, comprising following steps:

placing materials in said material carrier;

placing said material carrier at said center of said sublimation channel body;

tightening up and seal said two end pipes;

turning on said vacuum device to vacuum;

turning on said heating evaporation device to control said temperature between said center and said two ends of said sublimation channel body; and

cooling down said temperature and break relieving said vacuum after evaporation is completed, then scratch scratching and collect collecting products.

20(withdrawn). The vacuum sublimation purification process as claimed in claim 16, wherein conditions of sublimation for purifying Alq₃ are: evaporation temperature being $350\sim450^{\circ}$ C, condensation temperature being $250\sim350^{\circ}$ C, evaporation temperature being $50\sim100^{\circ}$ C higher than condensation temperature, and system pressure being $1\sim1$ 10^{-6} mbar.

21(withdrawn). The vacuum sublimation purification process as claimed in claim 16, wherein conditions of sublimation for purifying NPB are: evaporation temperature being 250~350°C, condensation temperature being 150~250°C, evaporation temperature being 30~80°C higher than condensation temperature, and system pressure being 0.1~1 10⁻⁶ mbar.

22(withdrawn). The vacuum sublimation purification process as claimed in claim 16, wherein conditions of sublimation for purifying CuPc are: evaporation temperature

Amendment dated: February 29, 2008 Reply to OA of: November 29, 2007

being 500~650°C, condensation temperature being 400~500°C, evaporation temperature being 50~100°C higher than condensation temperature, and system pressure being 0.1~1 10⁻⁶ mbar.